



PATENT APPLICATION

#916881
50 Response
6/5/03
Jewell

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Confirmation No: 4227

KABASAWA

Art Unit: 2881

Application Number: 09/629,618

Examiner: B. Souw

Filed: July 31, 2000

Atty. Docket No.: 107443-00007

For: ION IMPLANTATION APPARATUS AND ION IMPLANTATION METHOD

SUPPLEMENTAL AMENDMENT

Commissioner for Patents
Washington, D.C. 20231

April 16, 2003

Sir:

In further reply to the Office Action dated December 9, 2003, please consider the following remarks:

REMARKS

The Office Action dated December 9, 2003 has been received and carefully noted. This Amendment is Supplemental to the Amendment filed on April 9, 2003. Attached hereto please find a copy of the Handbook of Ion Implantation Technology, pages 675-692, edited by J.F. Ziegler, which was inadvertently omitted in the Amendment filed on April 9, 2003.

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